

APPARATUS AND METHOD FOR UTILIZING A MENISCUS IN SUBSTRATE PROCESSING

ABSTRACT OF THE DISCLOSURE

5 An apparatus for processing a substrate is provided which includes a proximity
head proximate to a surface of the substrate when in operation. The apparatus also
includes an opening on a surface of the proximity head to a cavity defined in the
proximity head where the cavity delivers an active agent to the surface of the substrate
through the opening. The apparatus further includes a plurality of conduits on the surface
10 of the proximity head that generates a fluid meniscus on the surface of the substrate
surrounding the opening.

(Fig. 2)